

FIG. 1

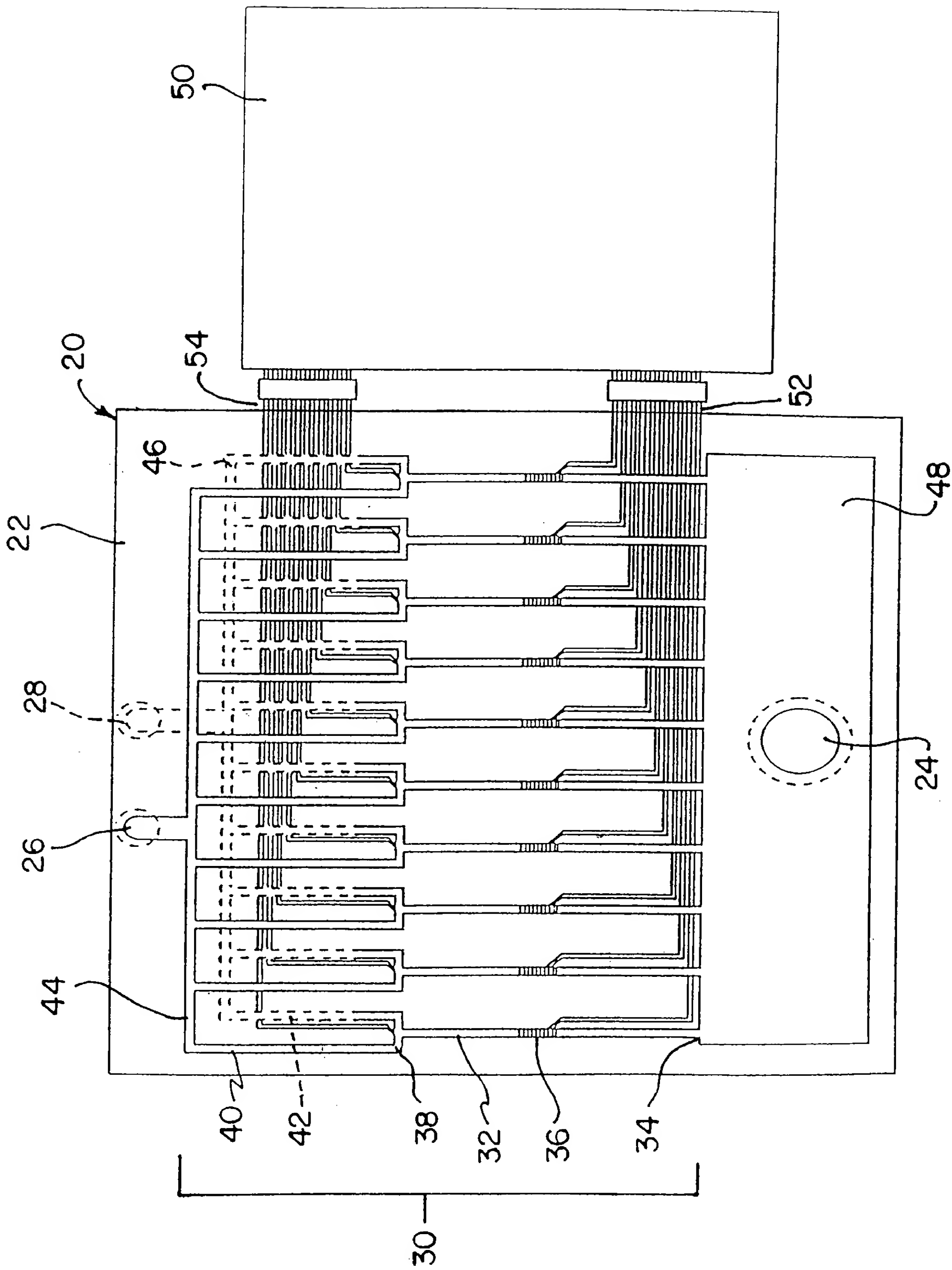


FIG. 2

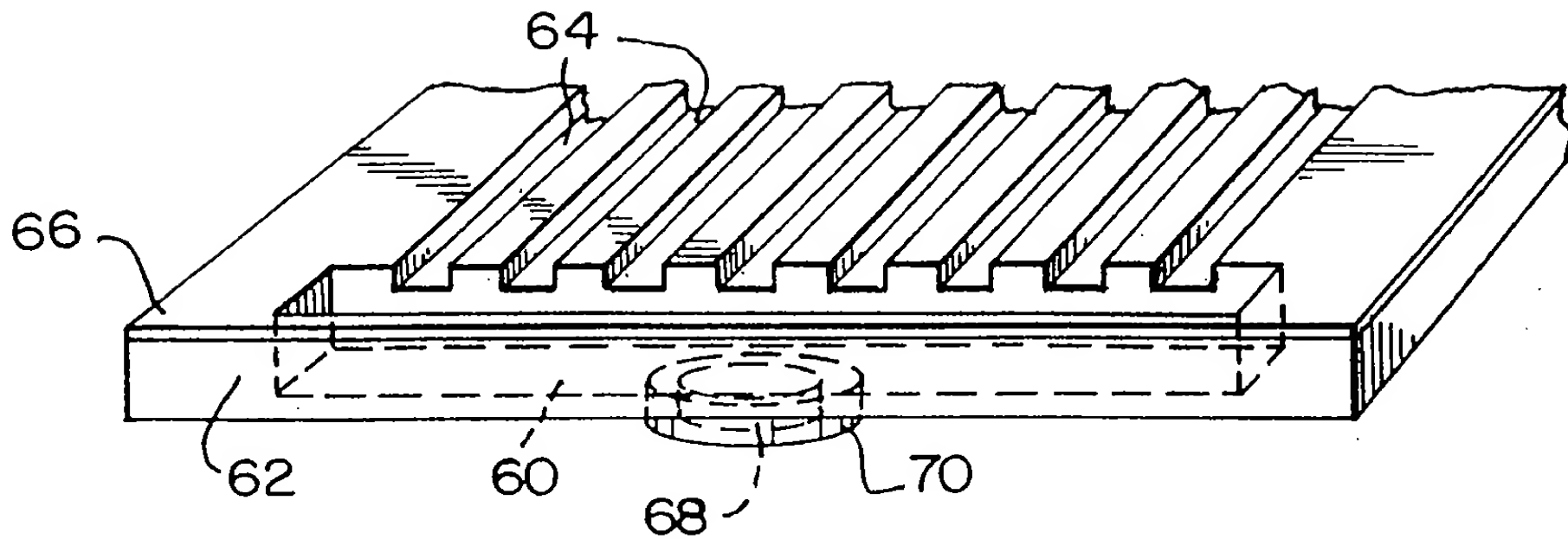


FIG. 3A

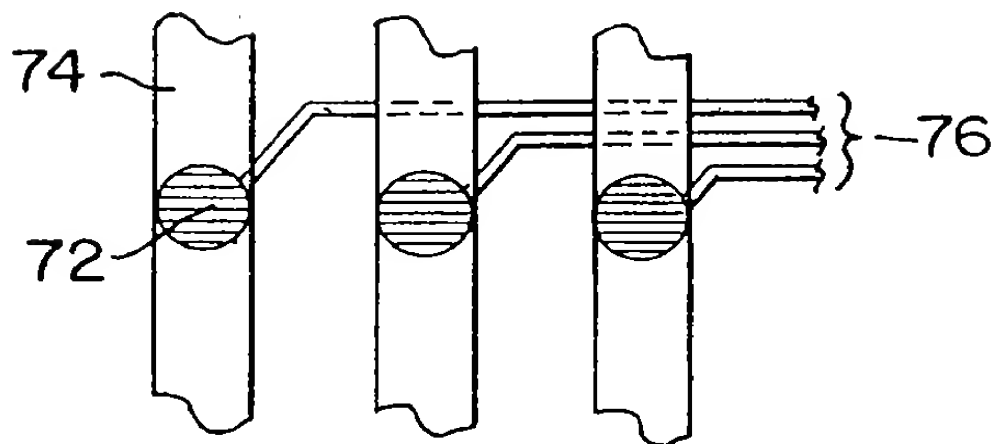


FIG. 3B

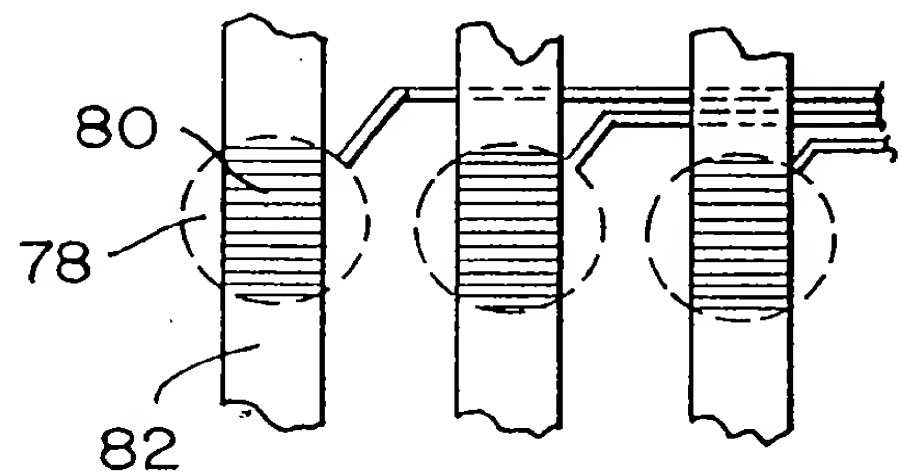


FIG. 4A

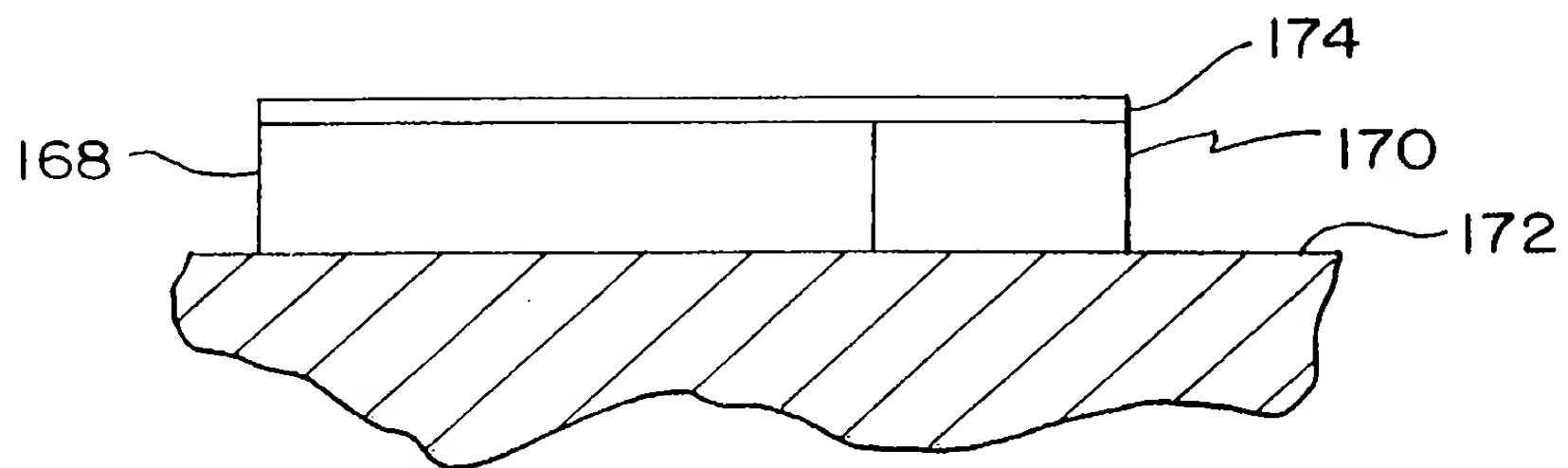


FIG. 4B

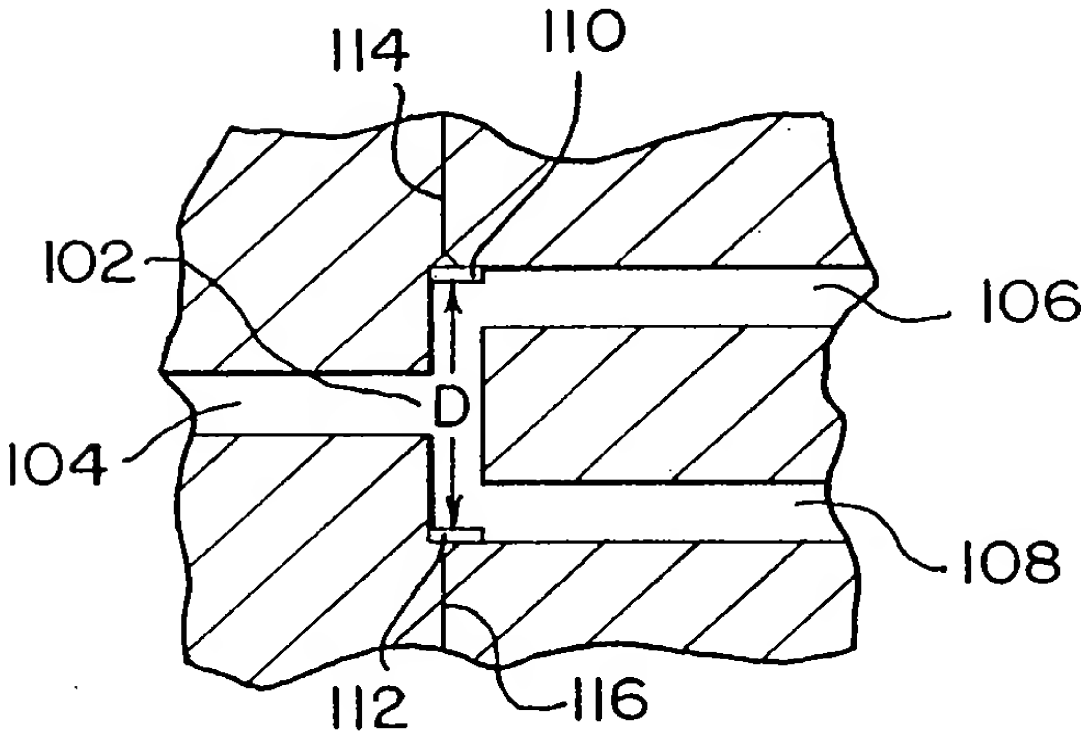
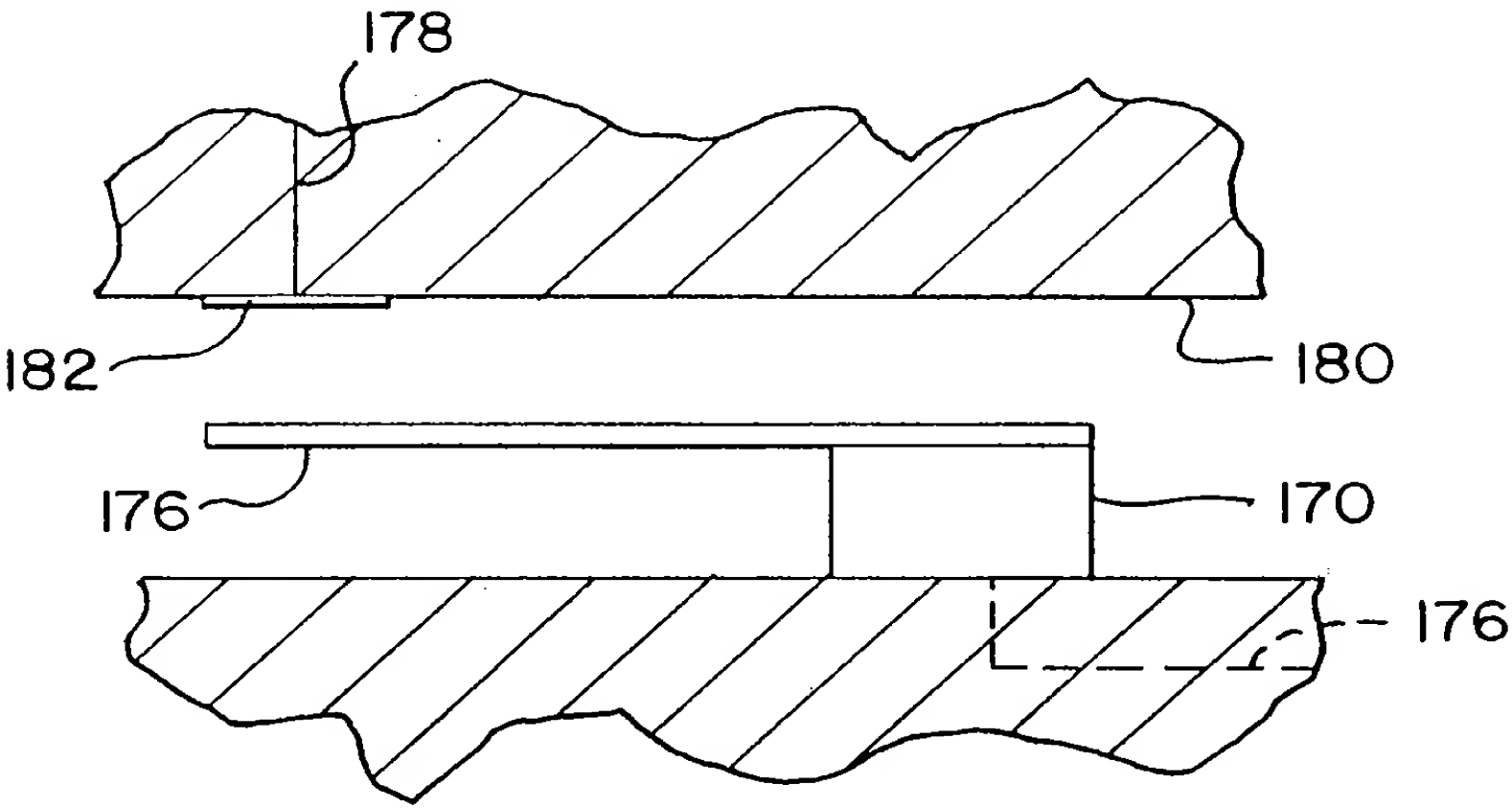


FIG. 5A

FIG. 5B

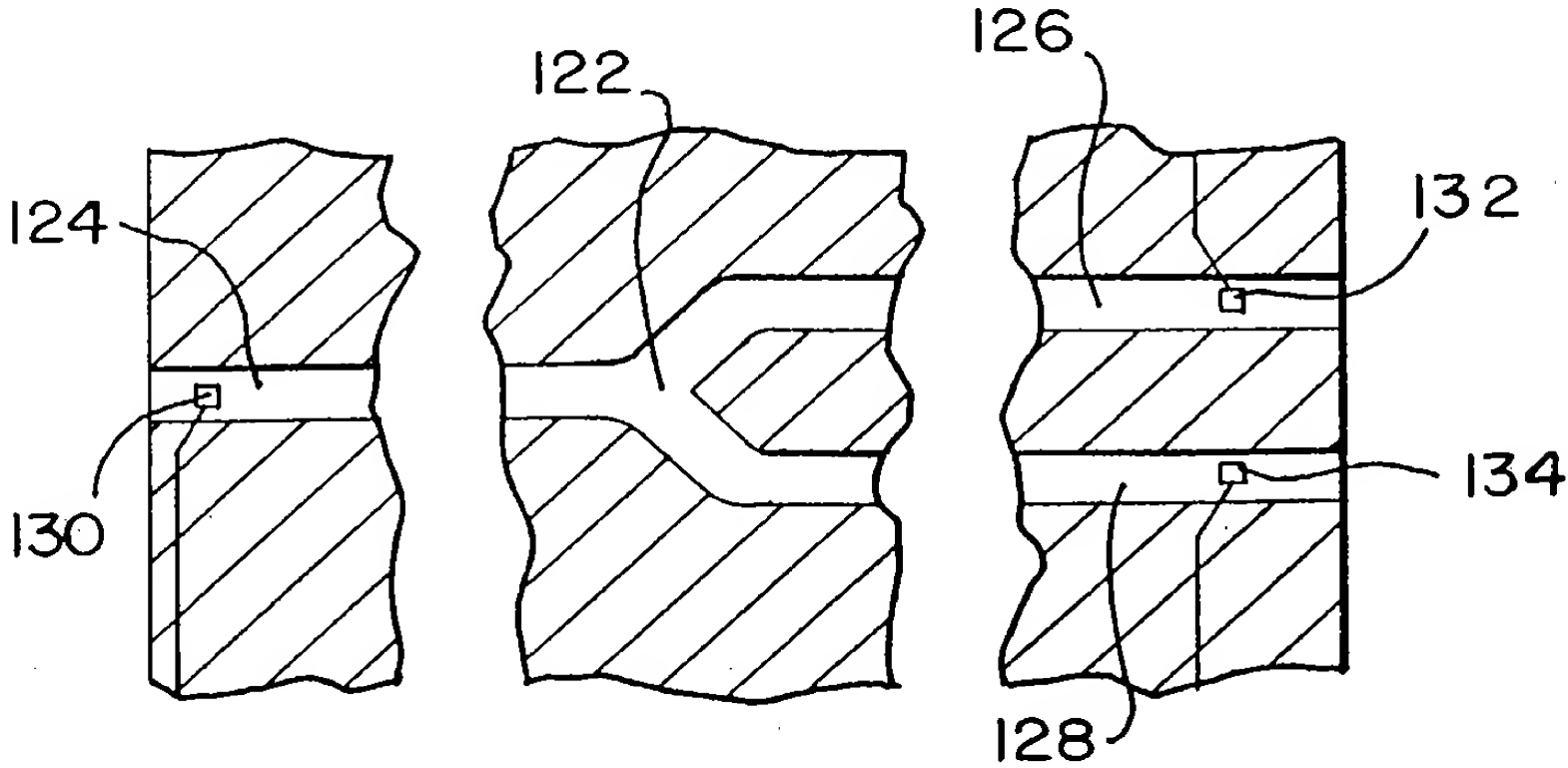


FIG. 5C

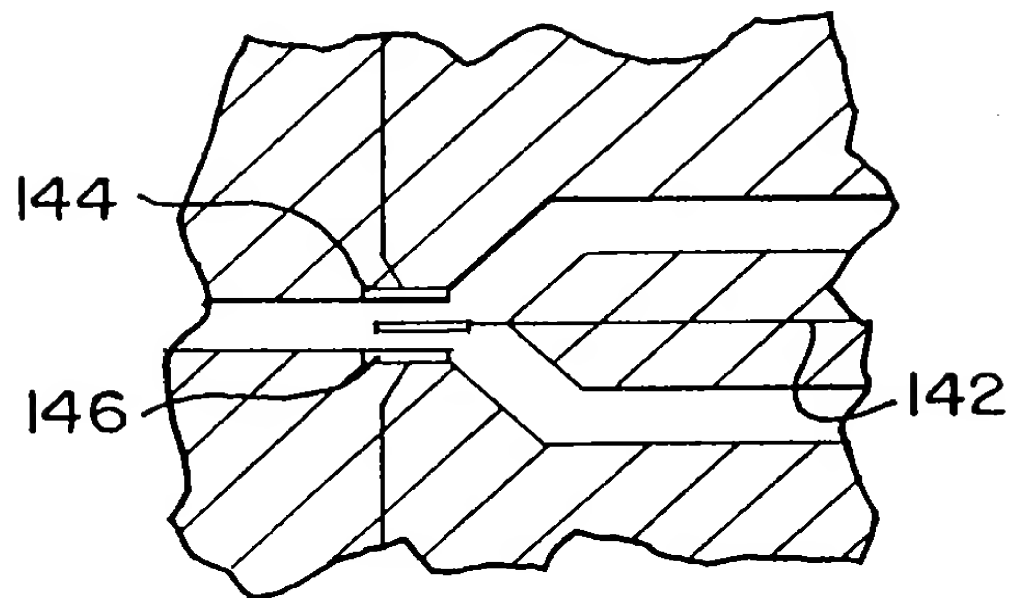


FIG. 5D

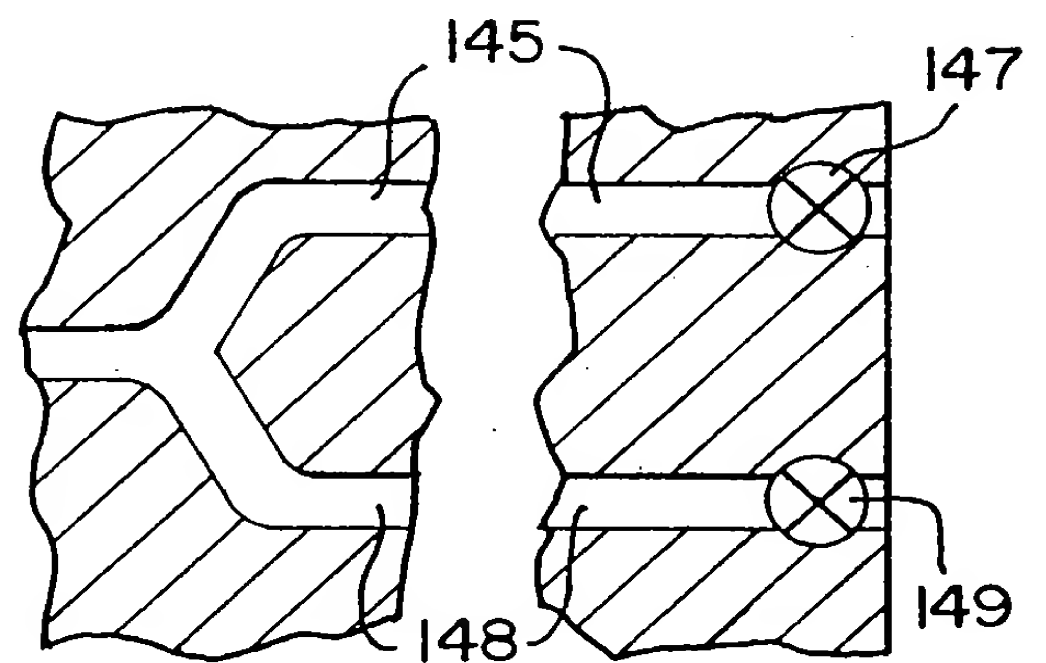
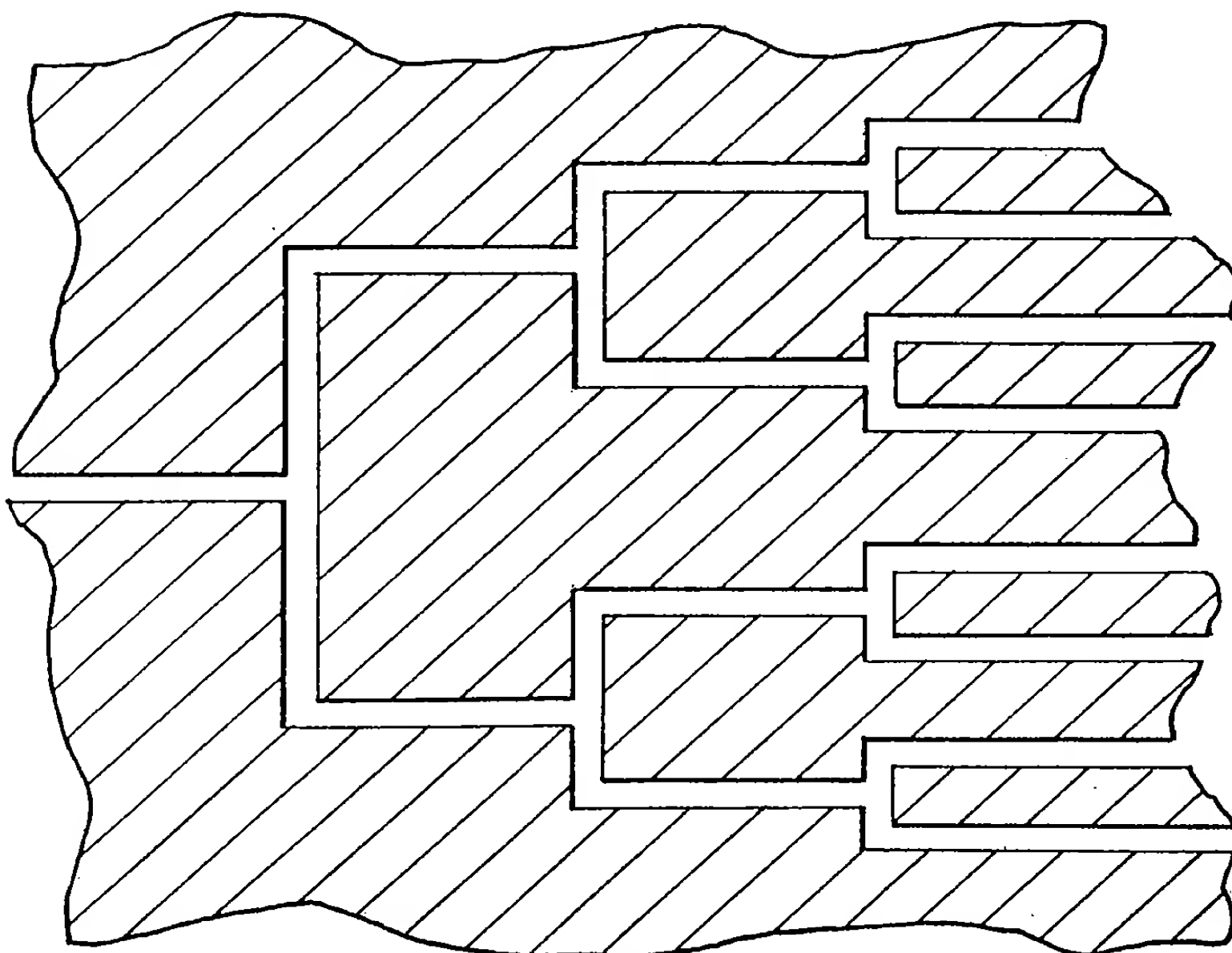


FIG. 6



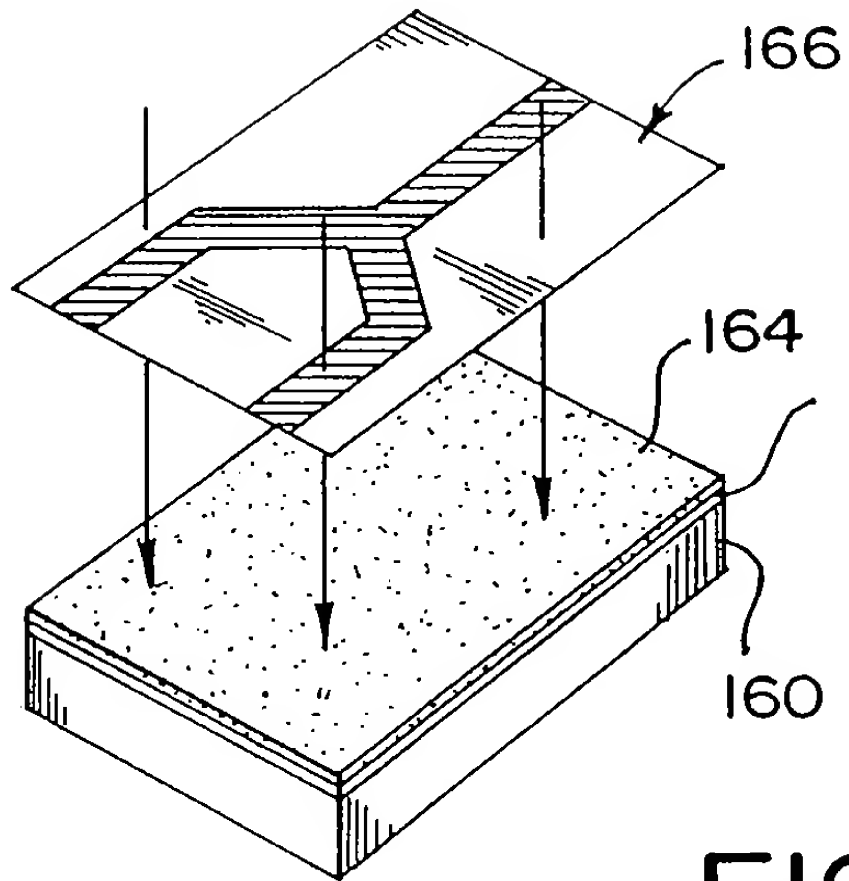
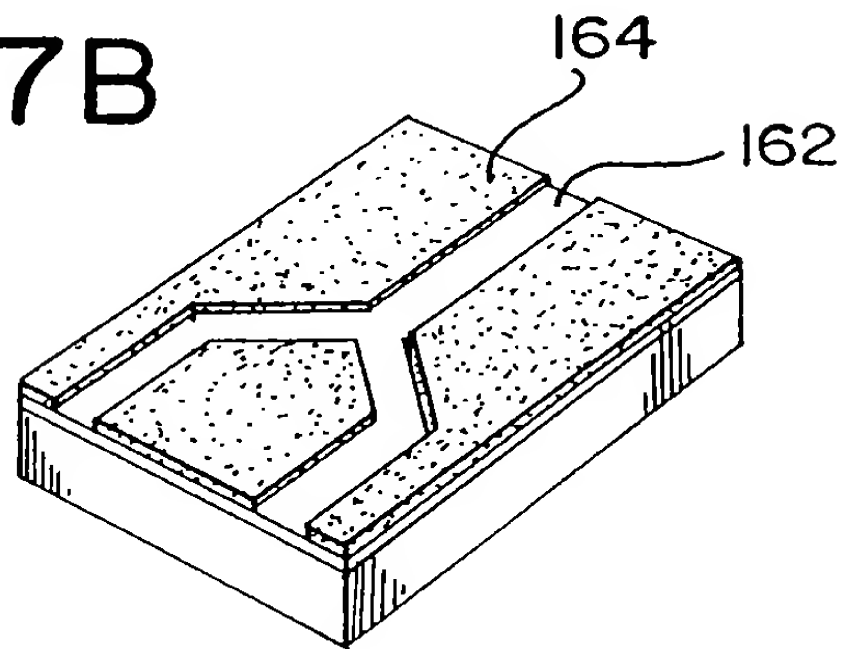


FIG. 7A

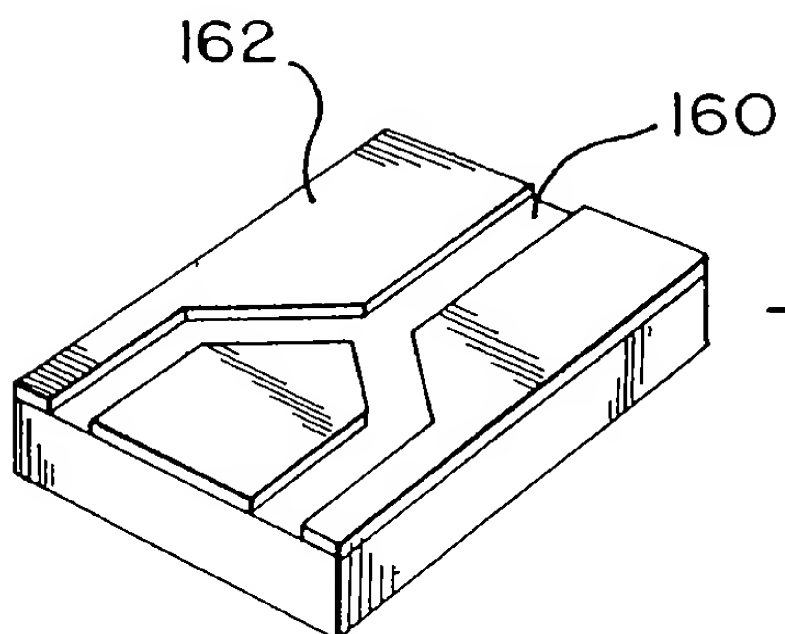
DEVELOP  
& RINSE → TO FIG. 7B

FIG. 7B



TO FIG. 7C ← 1. ETCH  $\text{SiO}_2$   
2. REMOVE RESIST

FIG. 7C



ETCH Si → TO FIG. 7D

FIG. 7D

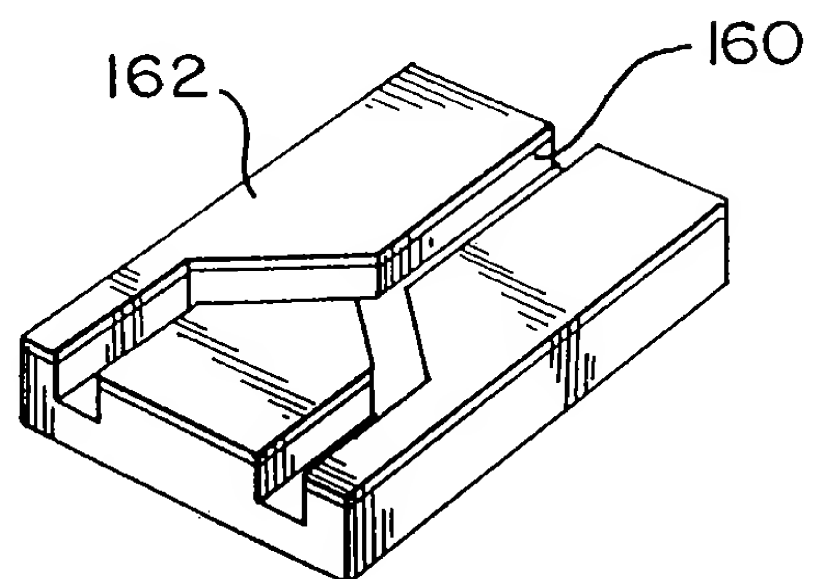
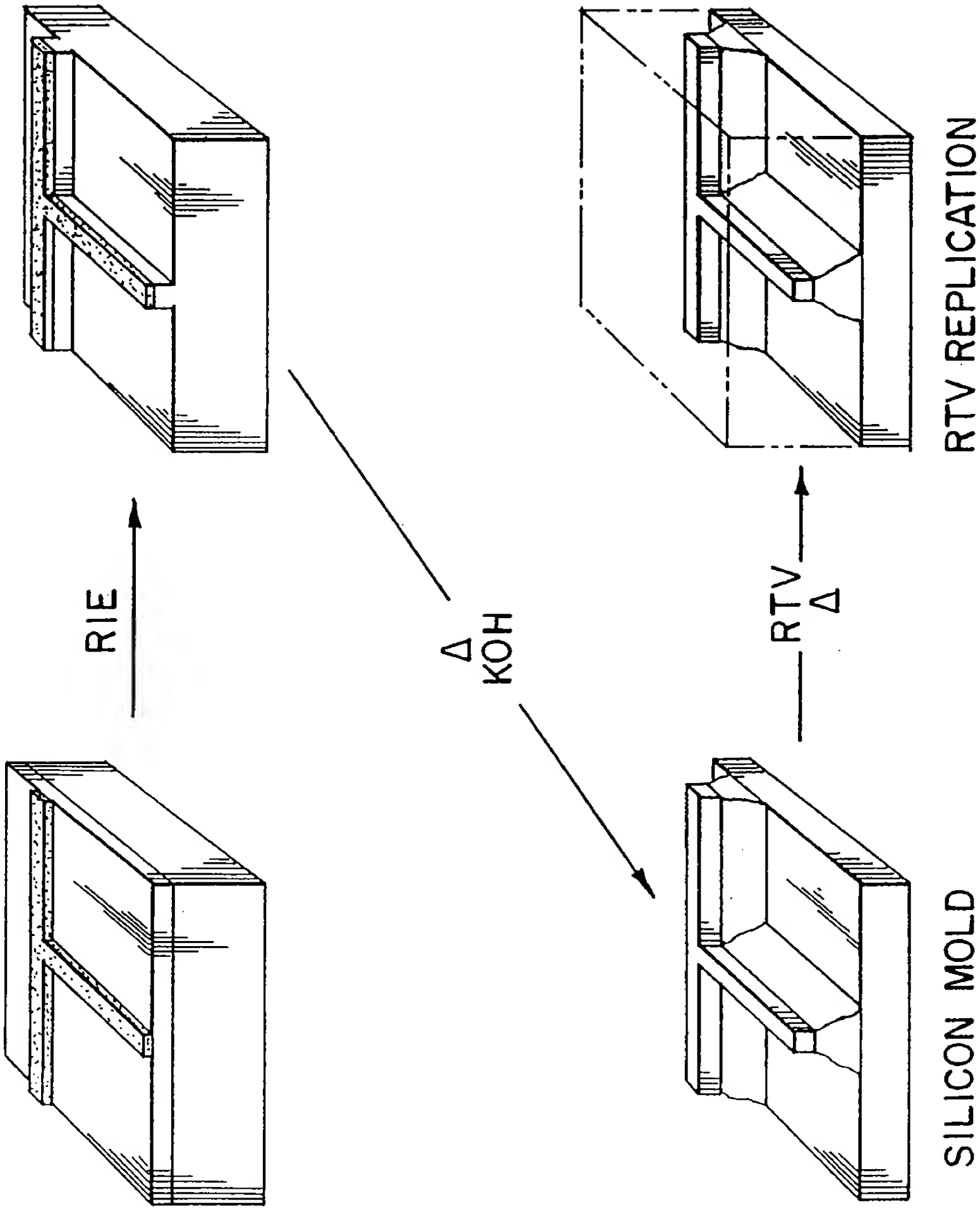


FIG. 8



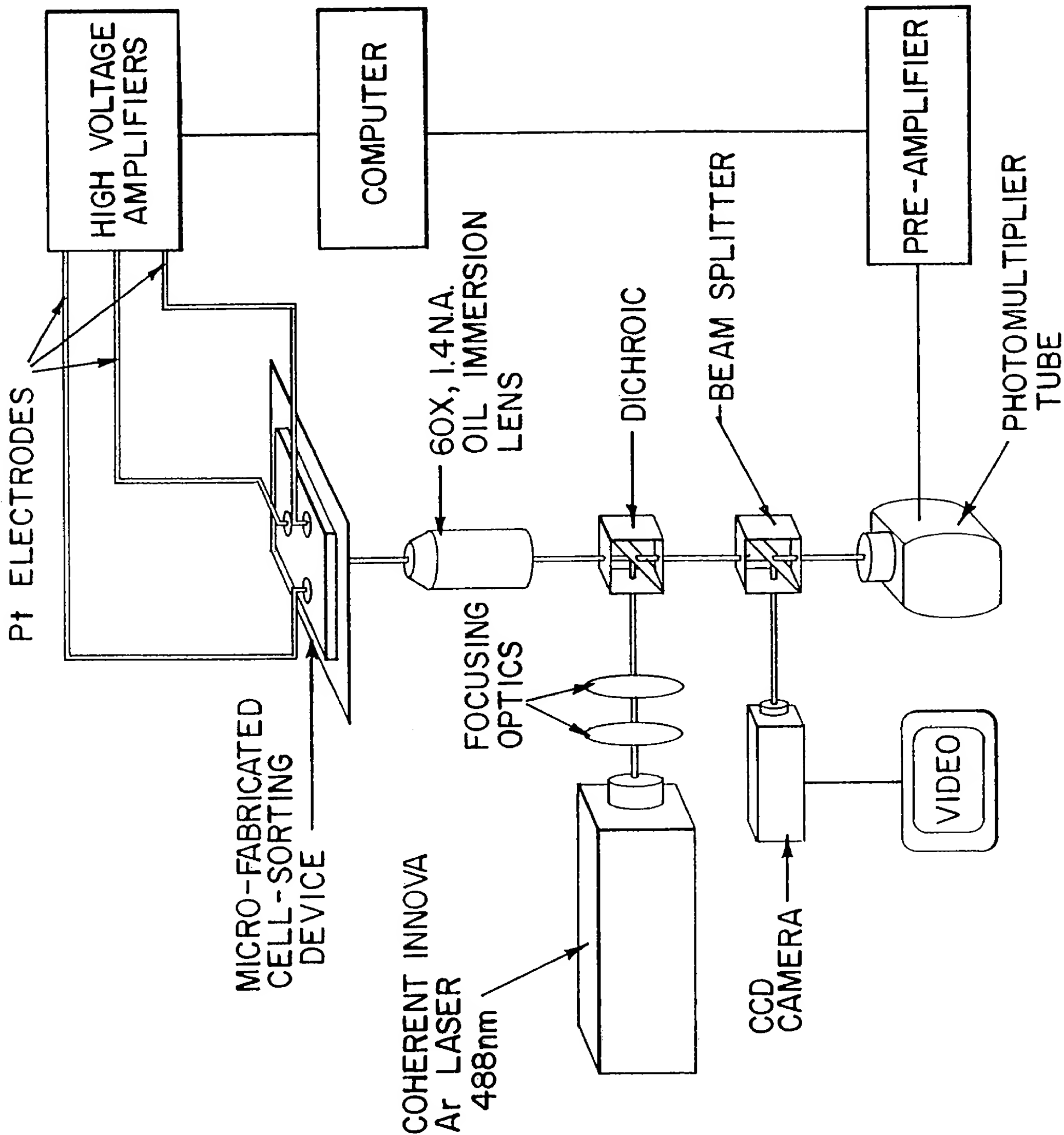


FIG. 9

FIG. 10

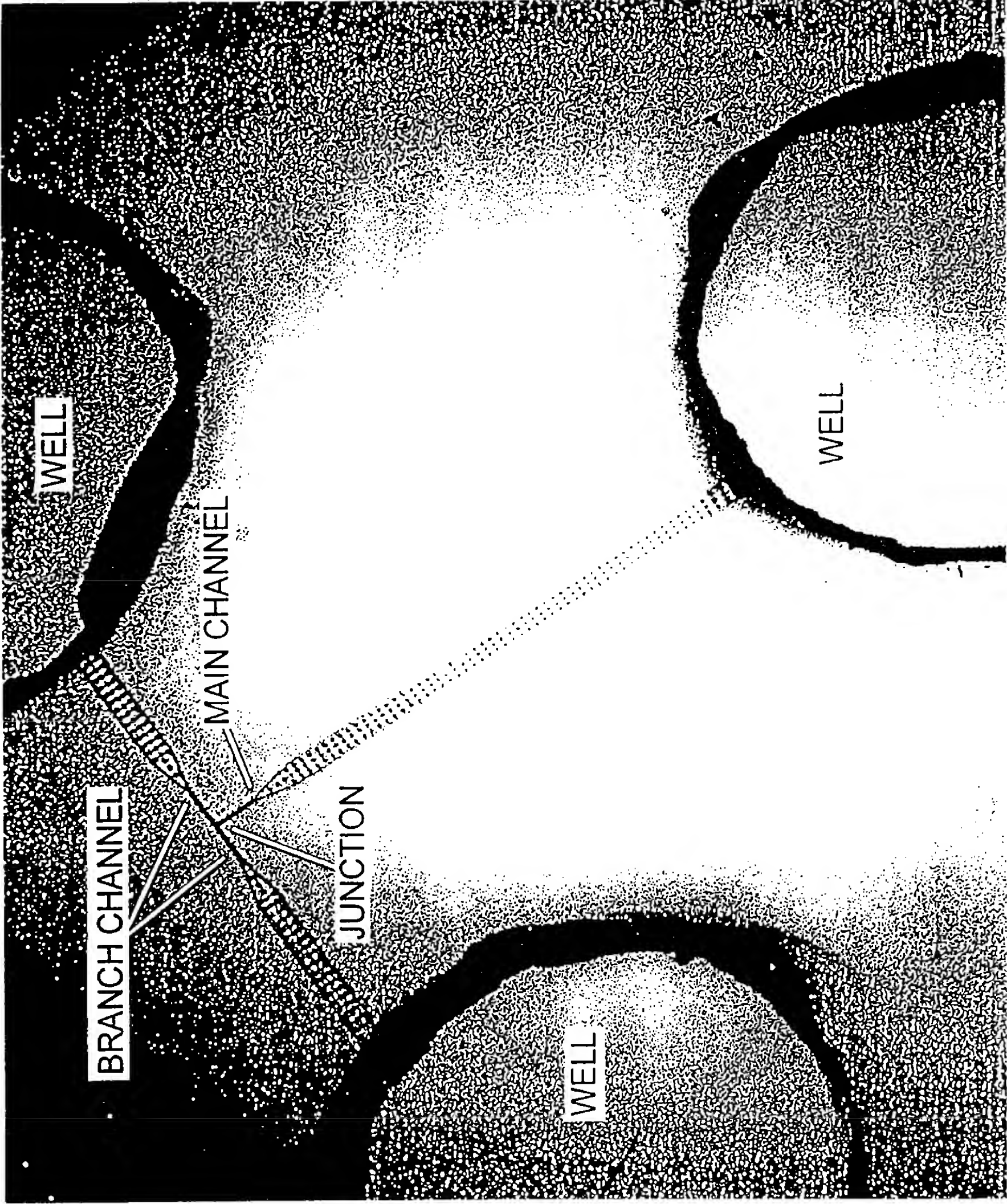




FIG. IIA

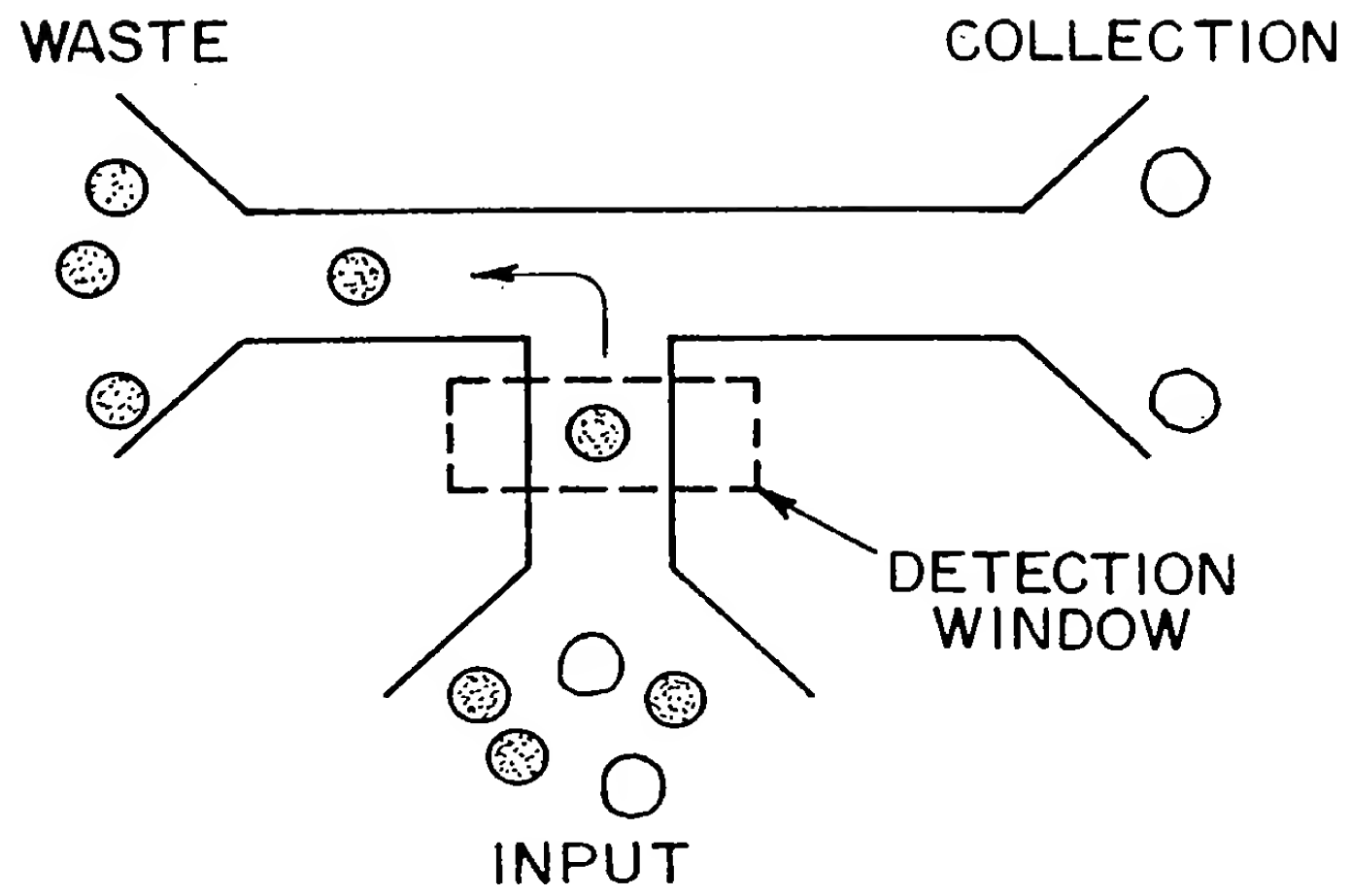


FIG. IIB

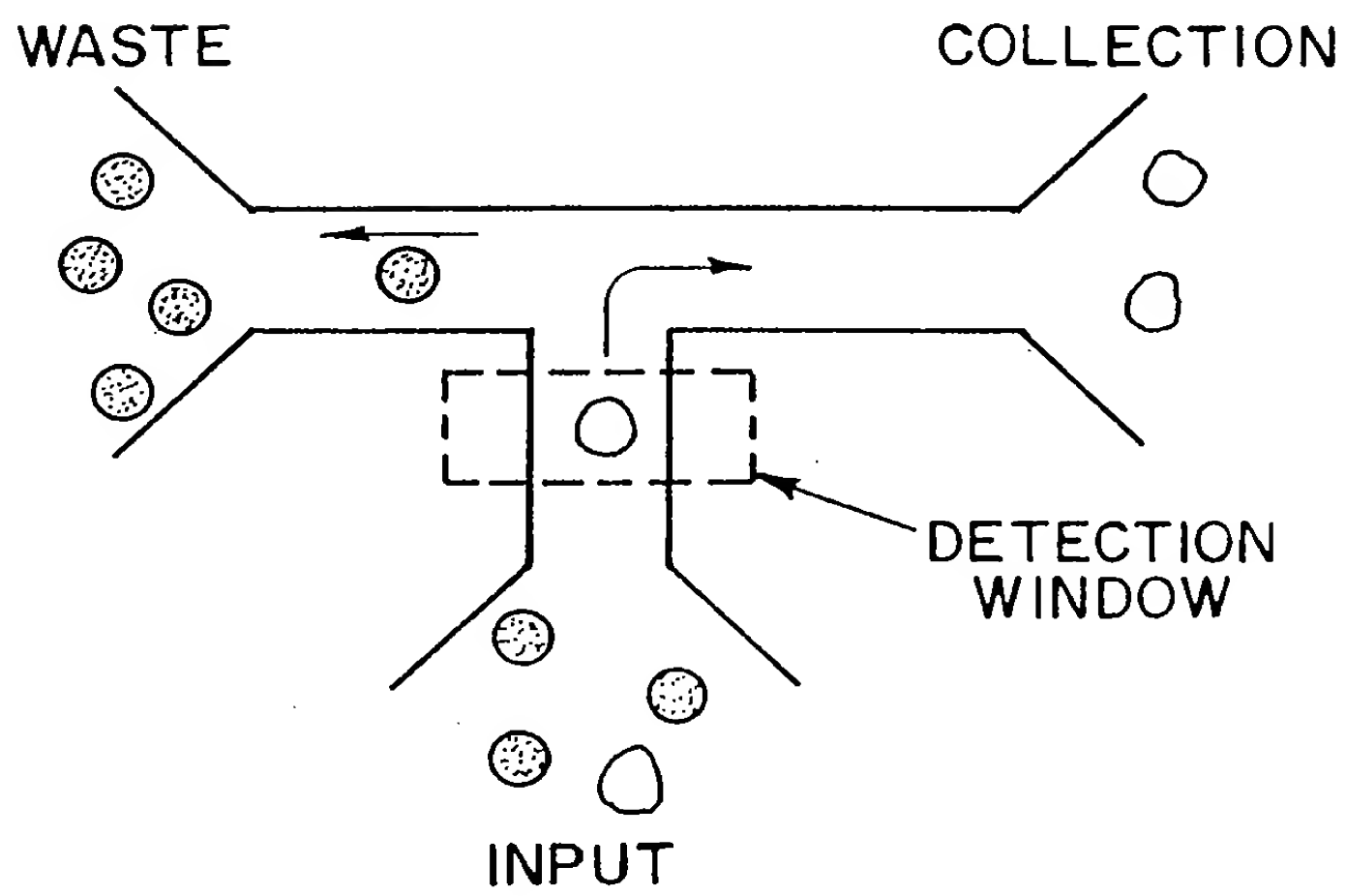


FIG. 12A

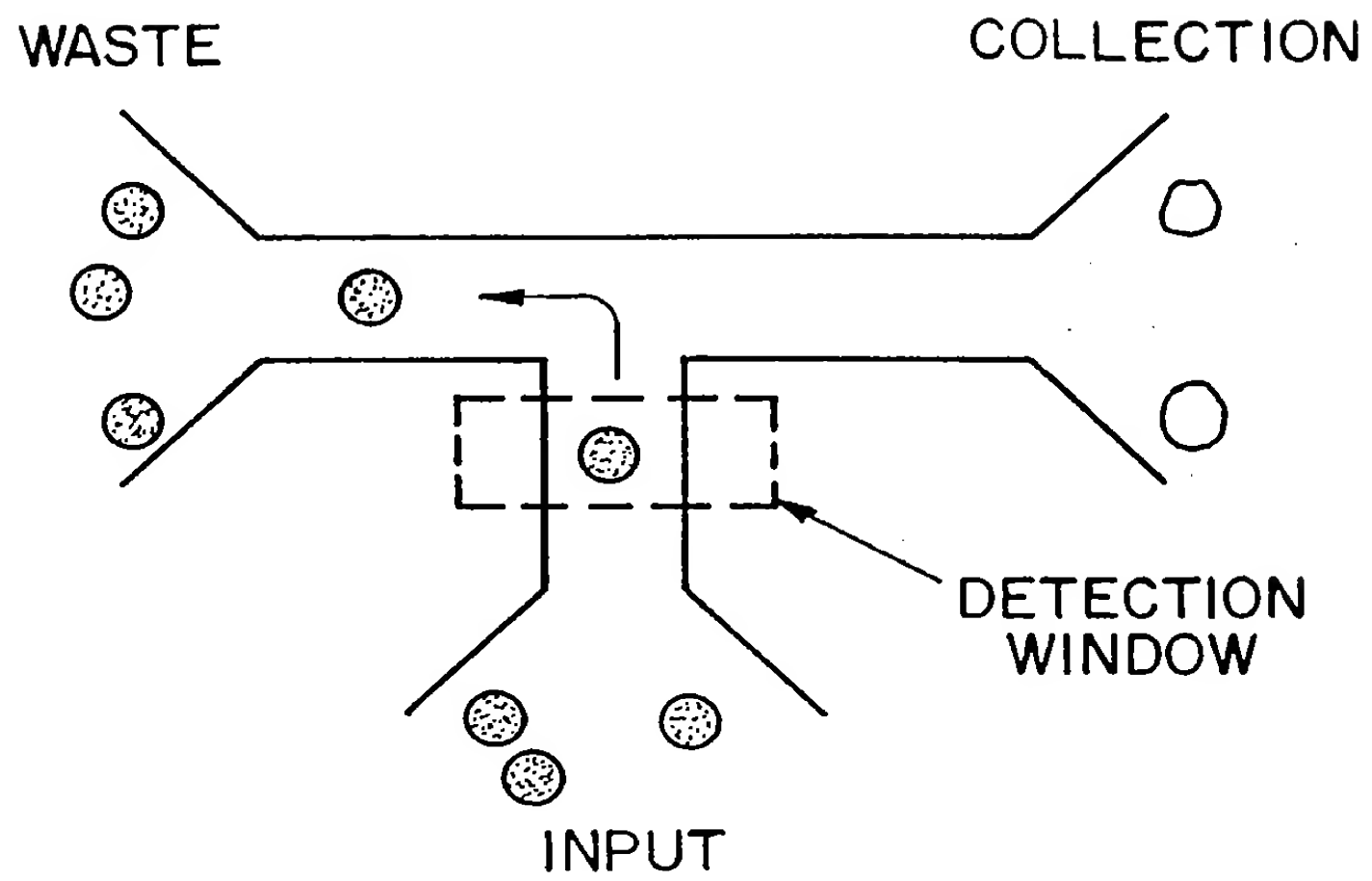
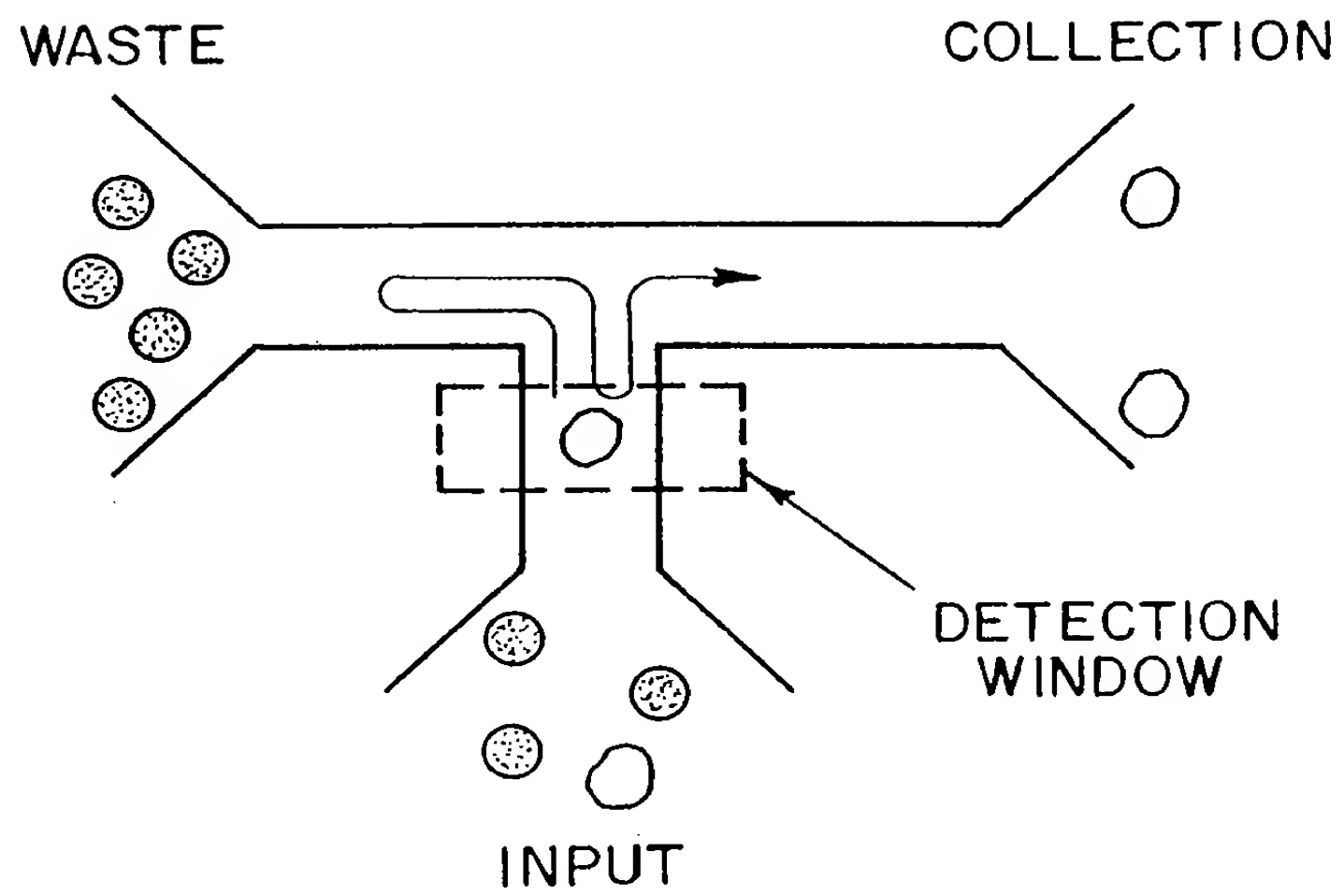
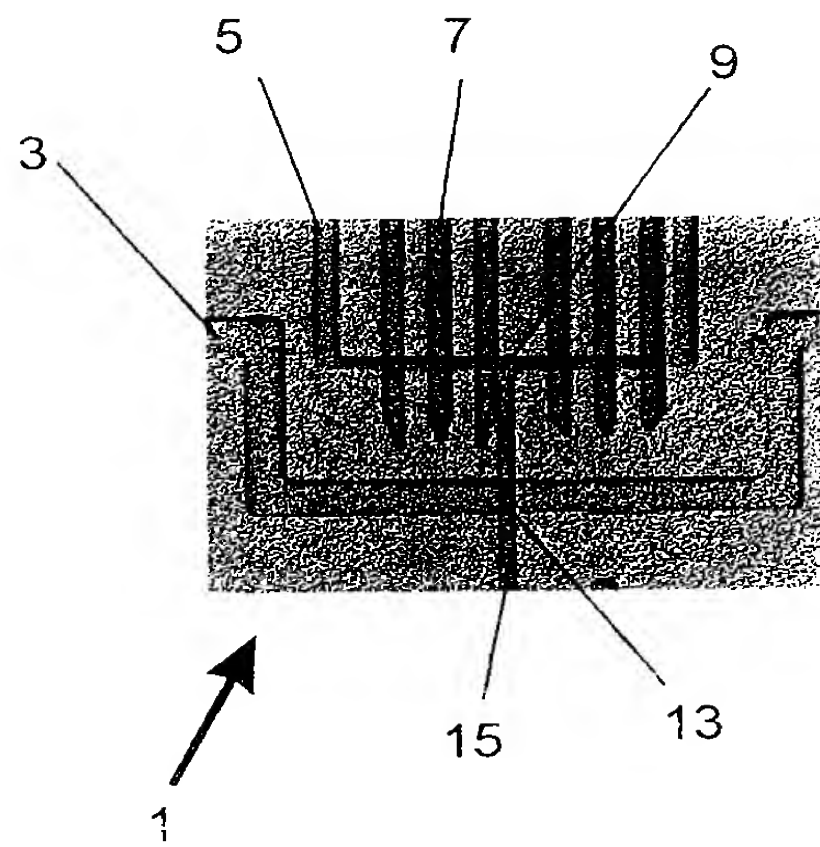
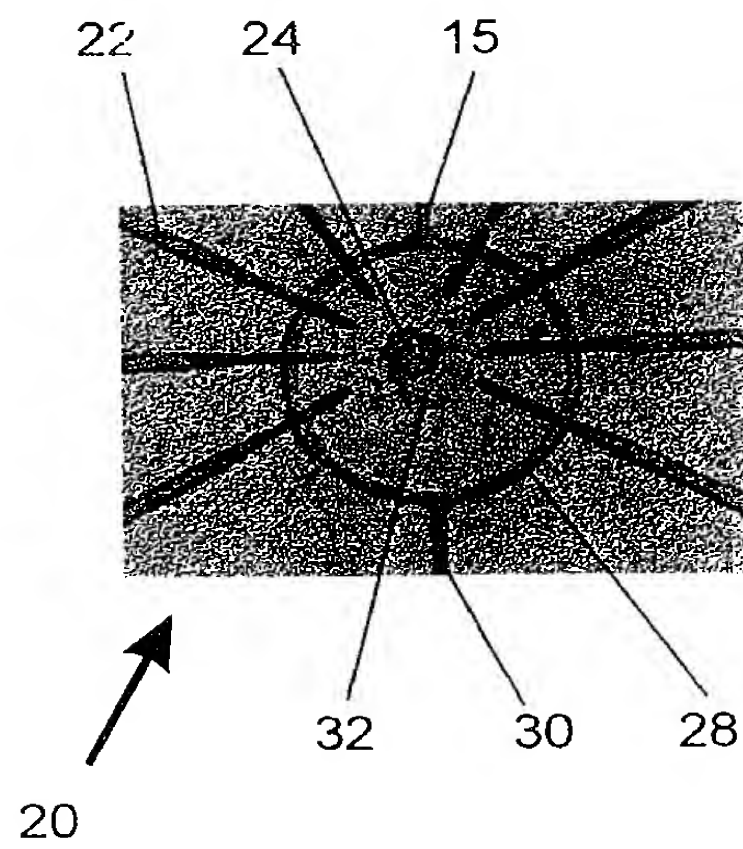


FIG. 12B



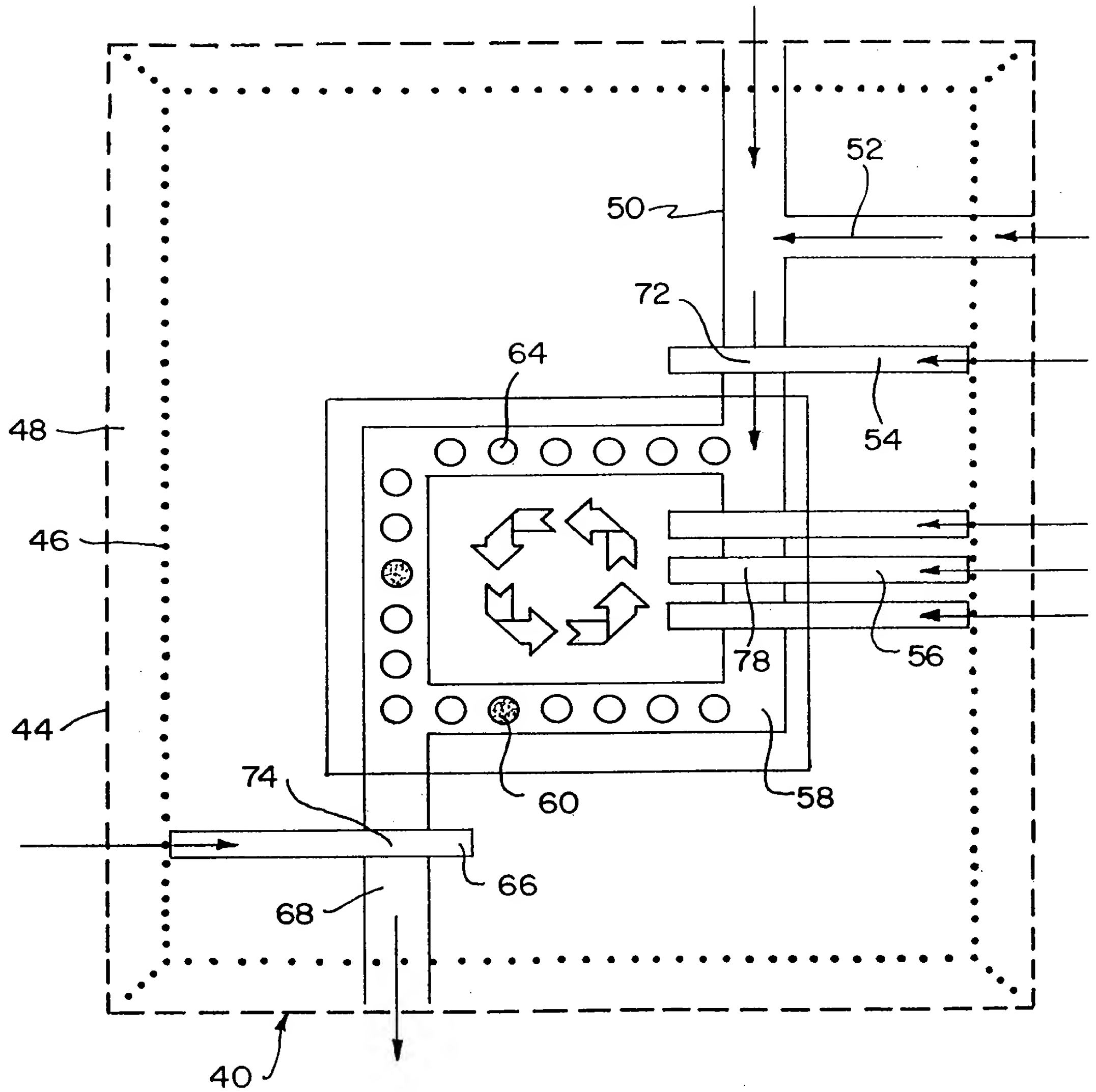


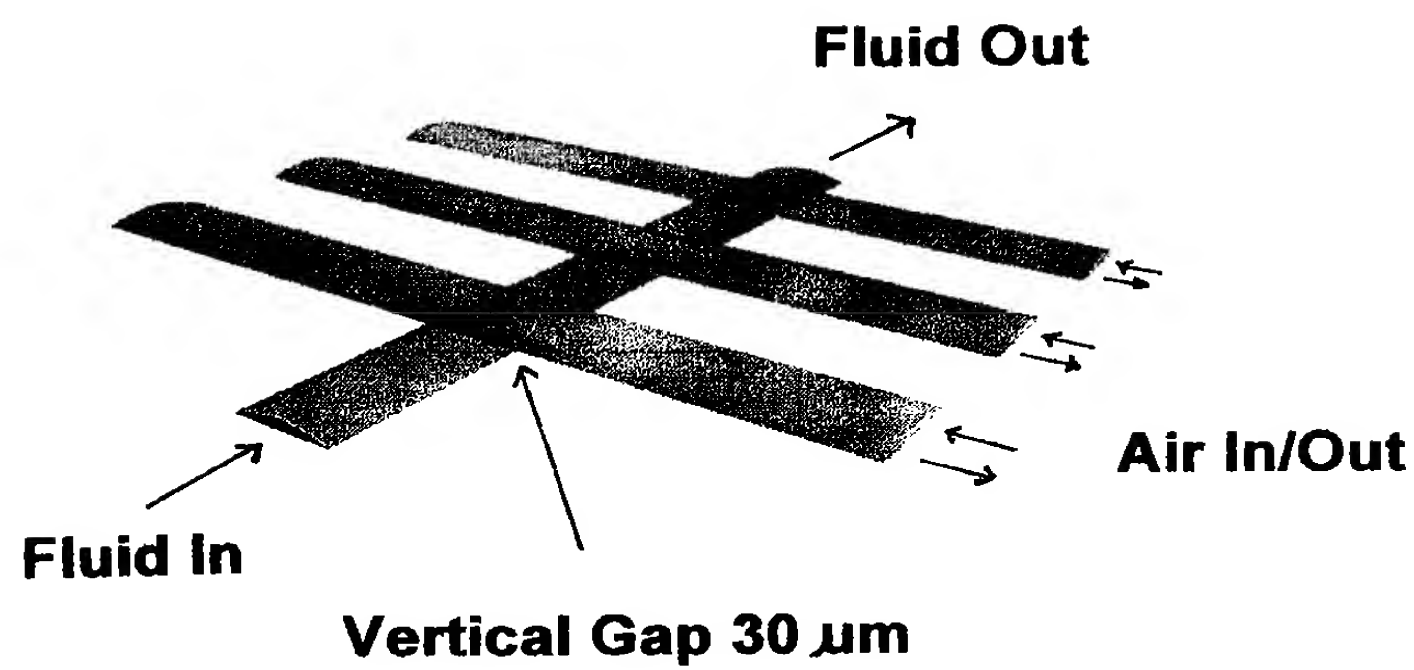
**FIG. 13A**



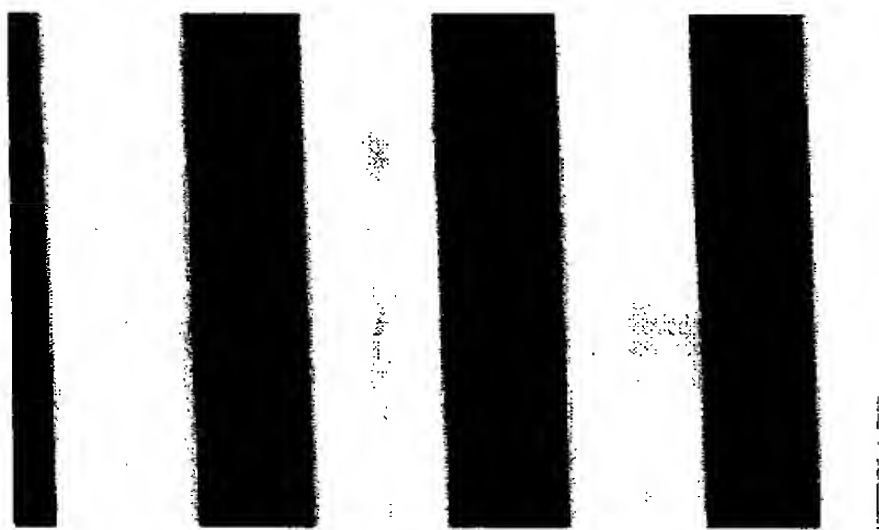
**FIG. 13B**

FIG. 14





**FIG. 15**



**FIG. 16A**



**FIG. 16B**



**FIG. 16C**

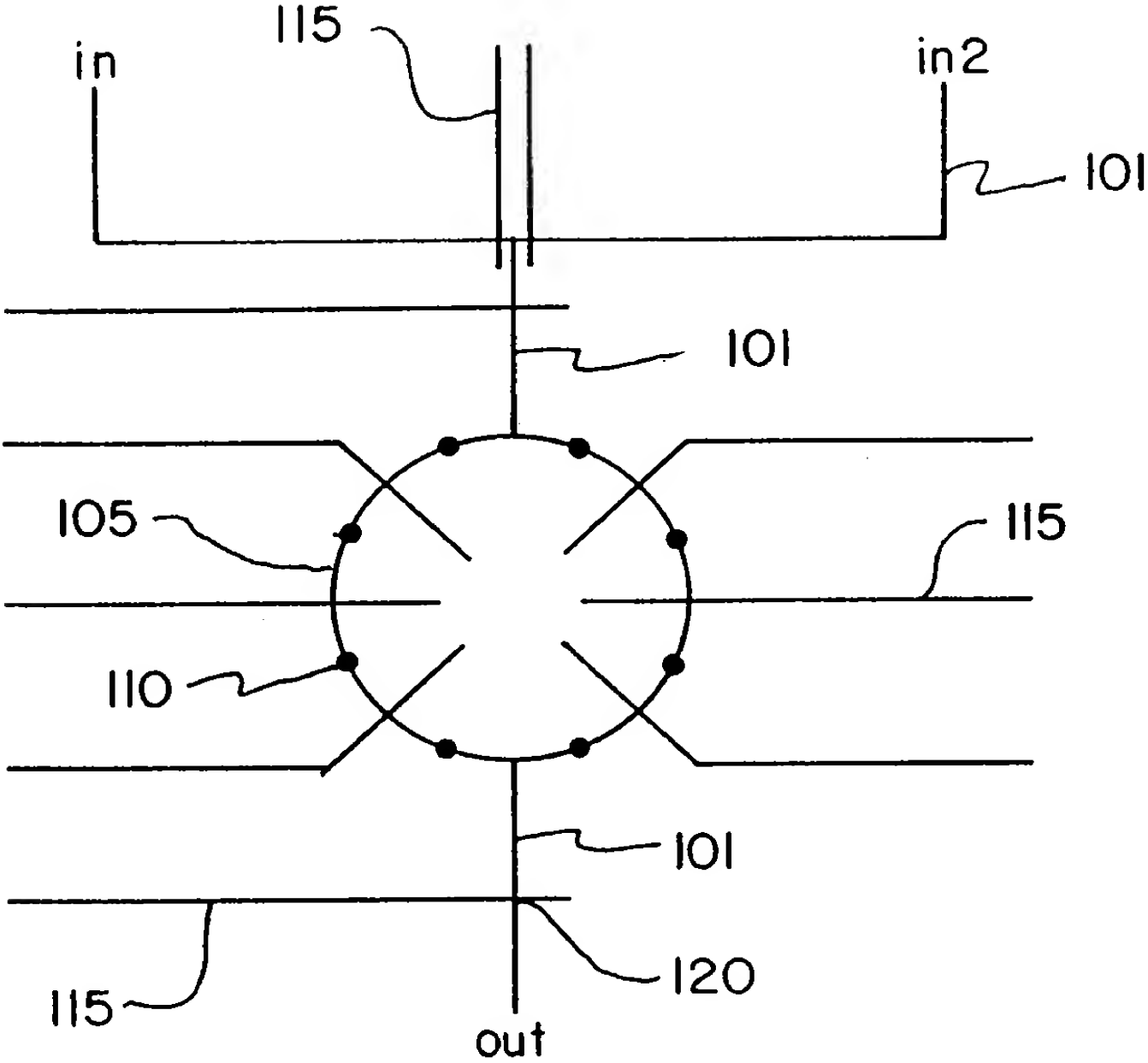
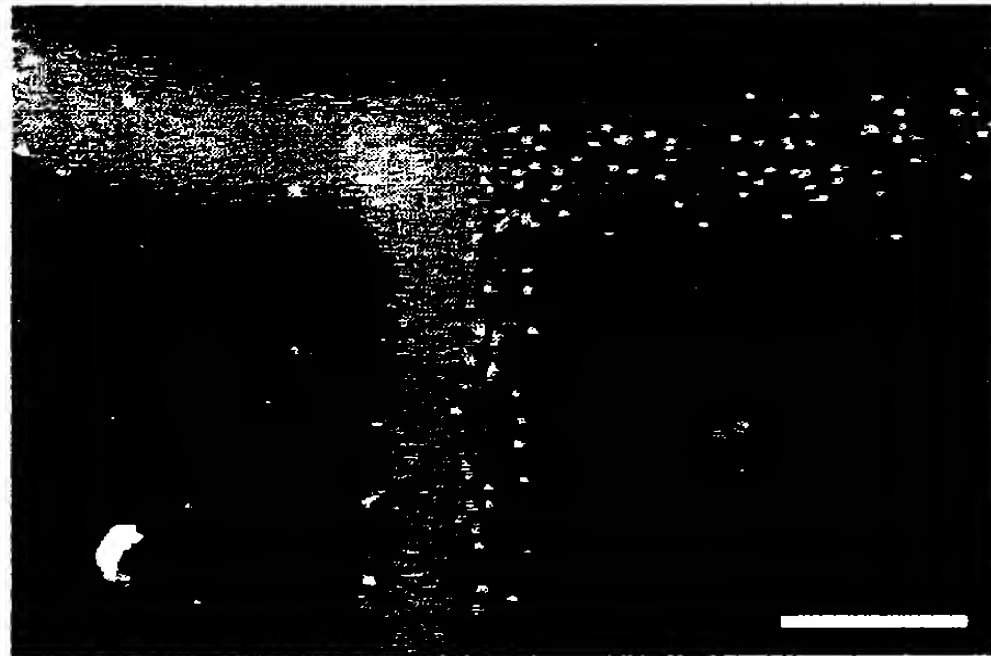
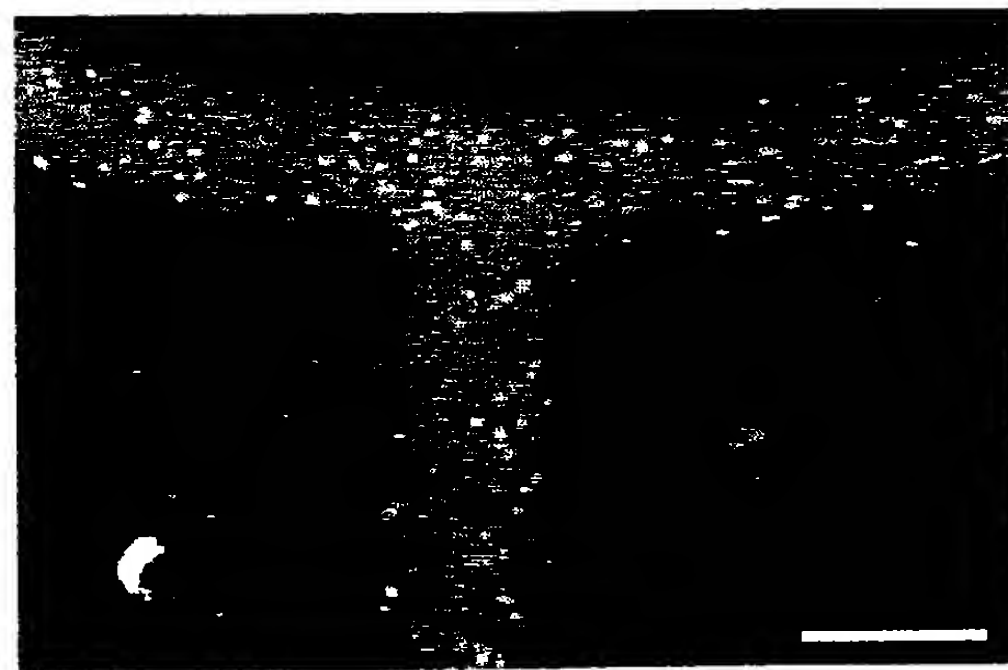


FIG. 17

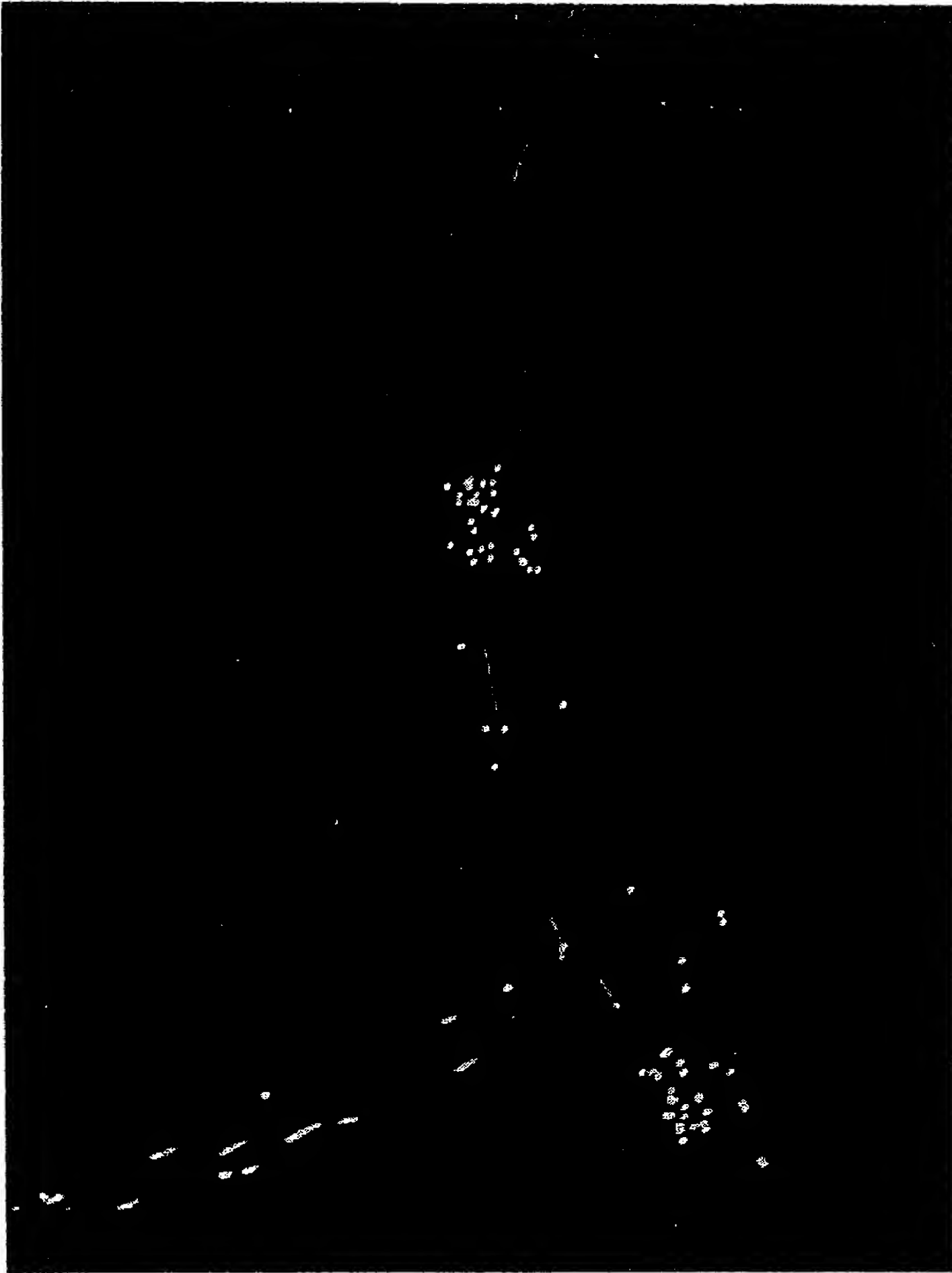


**FIG. 18A**



**FIG. 18B**





**FIG. 19**

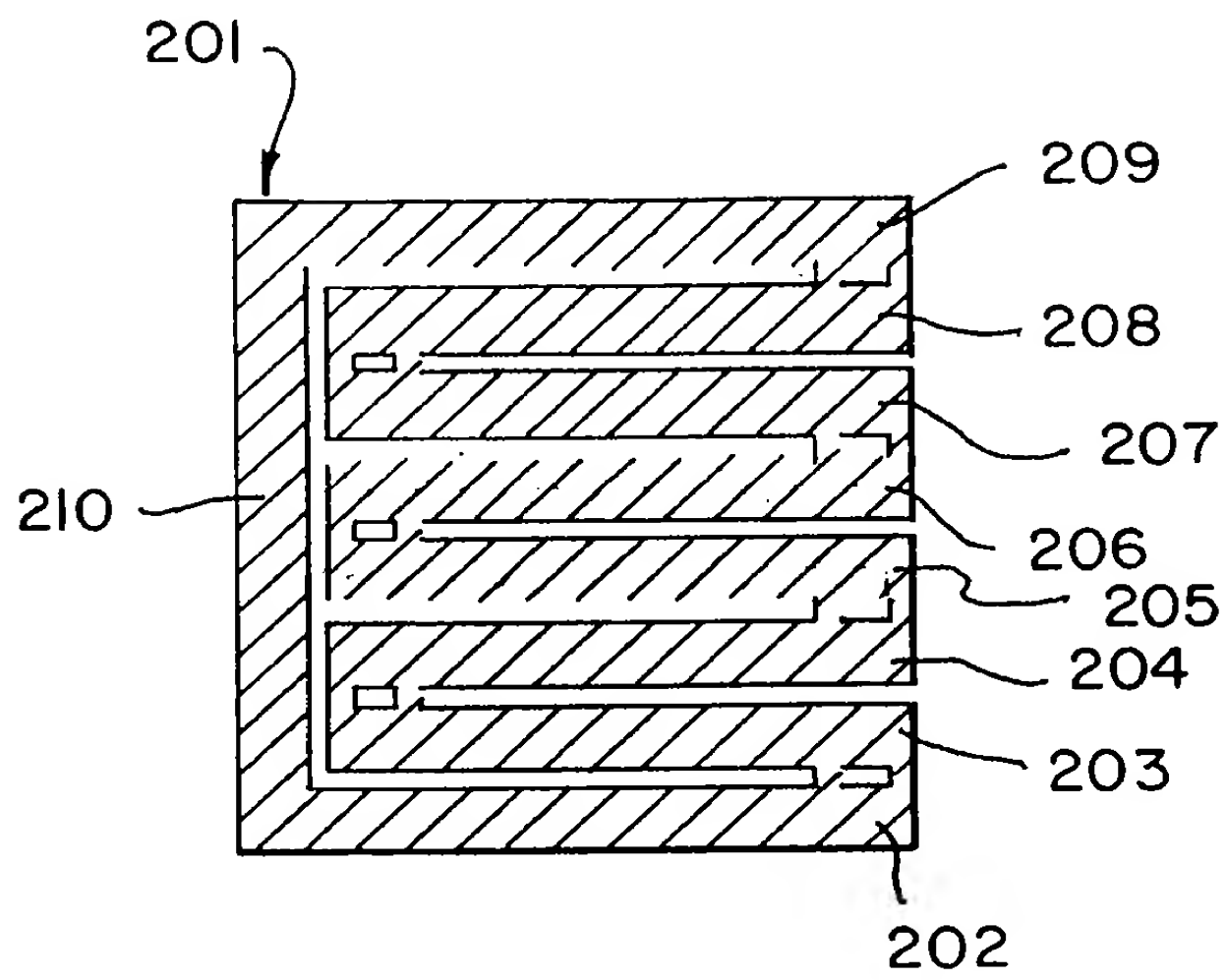


FIG. 20

FIG. 21A

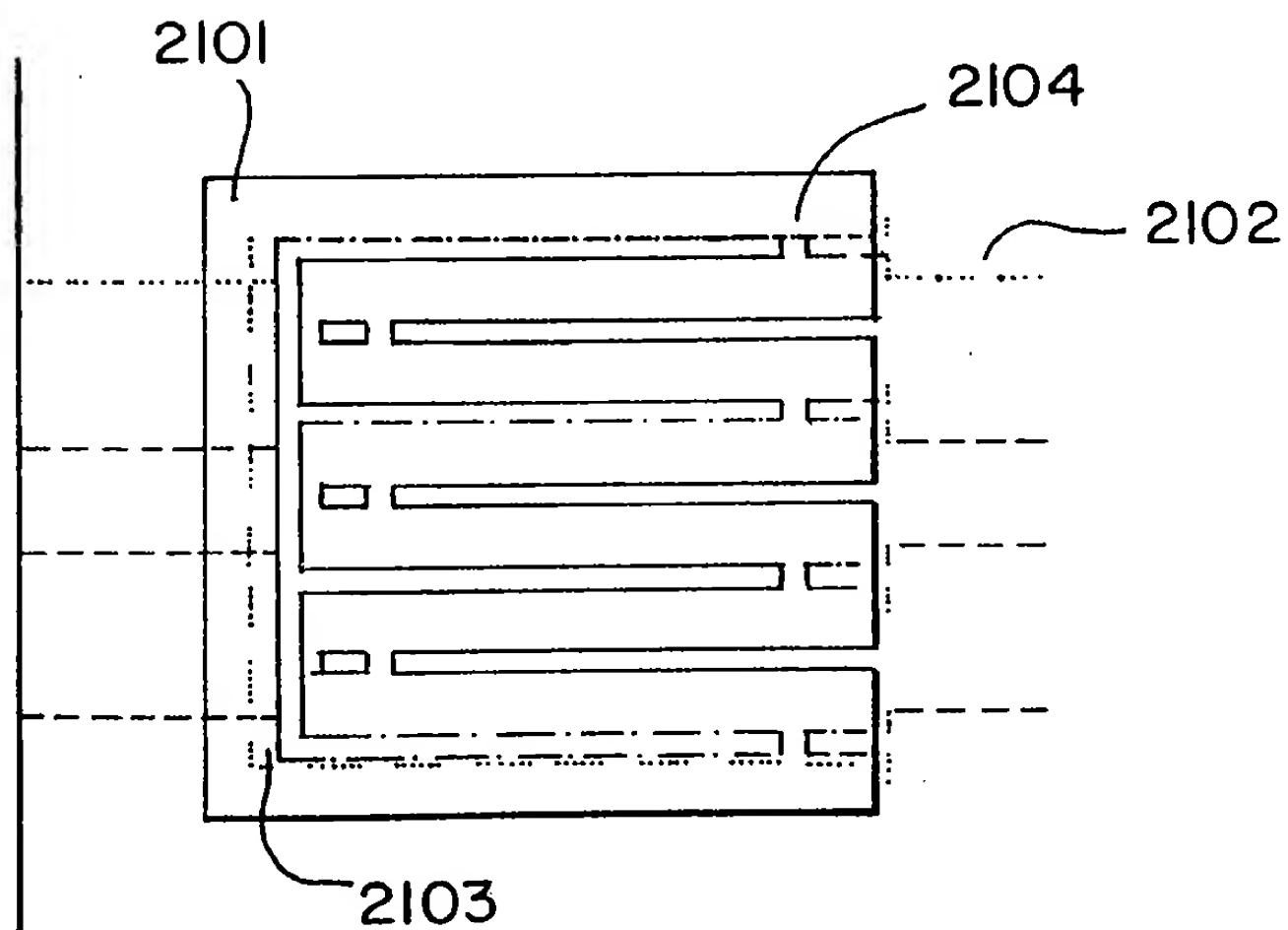
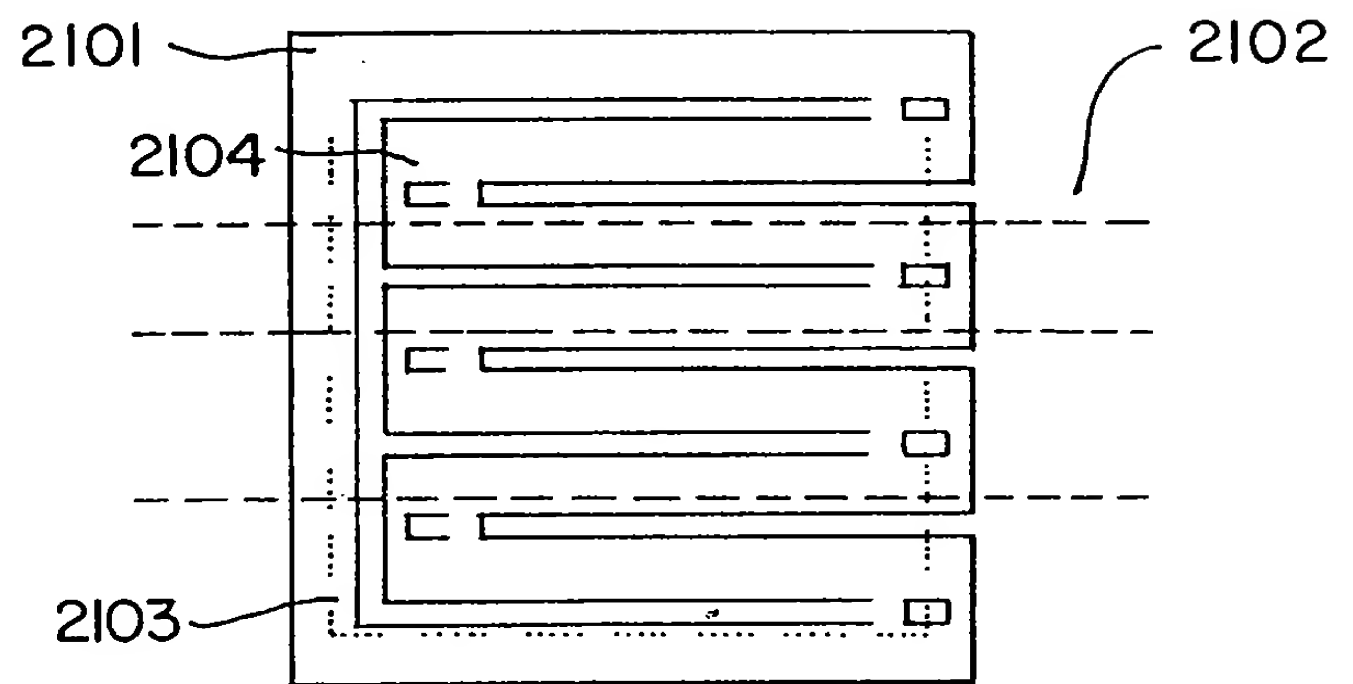


FIG. 21B

FIG. 22A

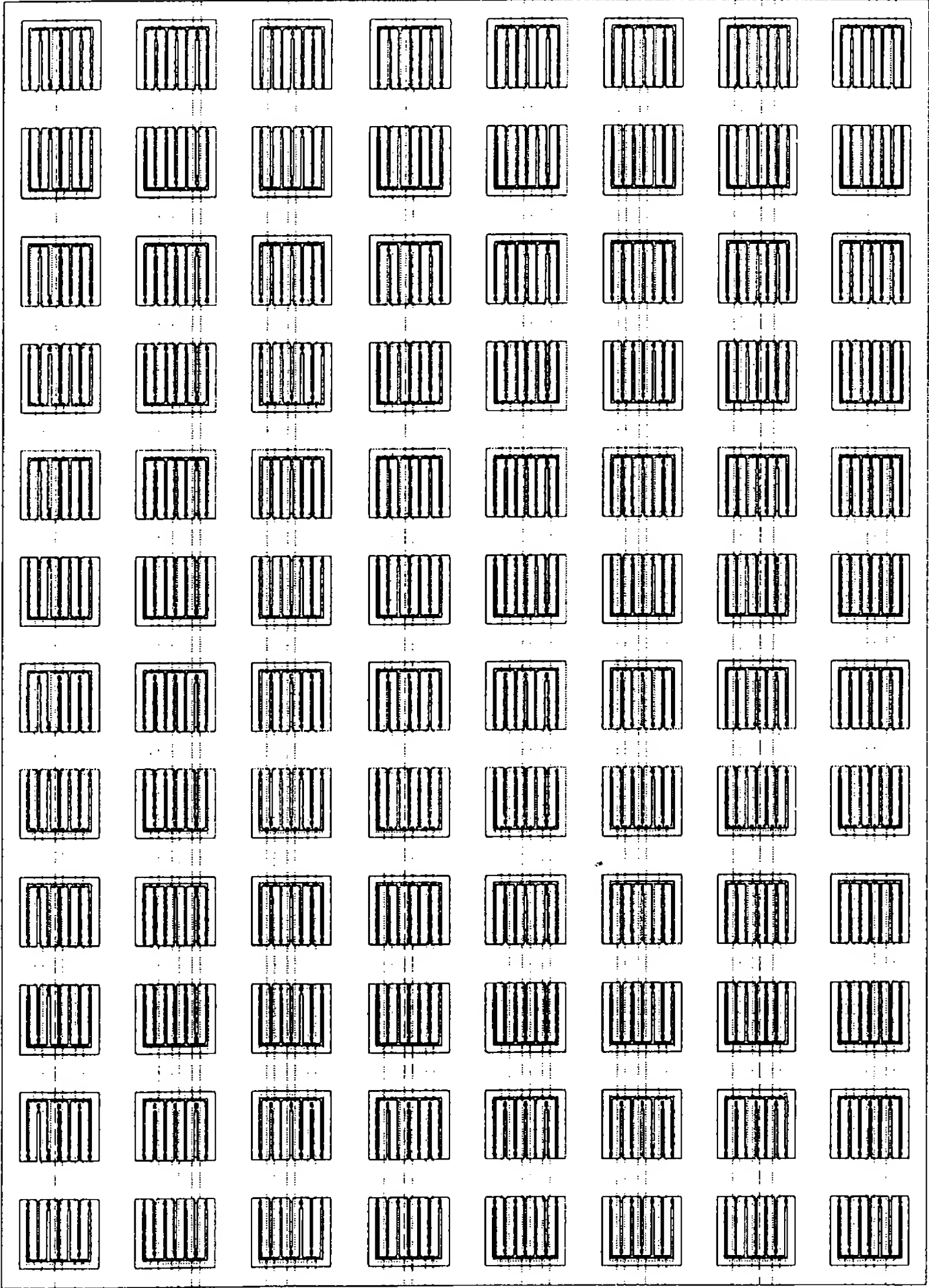


FIG. 22B

